

IN THE SPECIFICATION:

Please amend the specification as follows:

Please delete Page 6, lines 20 and 21 as follows:

~~FIGS. 14A, 14B, 14C and 14D demonstrate a technique for measuring bandwidth.~~

~~FIGS. 14E-H show features of etalons used for bandwidth measurement.~~

Please amend Page 6, line 27 as follows:

FIGS. 19 and 19A through 19GD5 show features of a purge system.

Please amend the second paragraph on Page 46 as follows:

Gas Control

The preferred embodiment of this invention has a gas control module as indicated in FIG. 1 and it is configured to fill each chamber with appropriate quantities of laser gas. Preferably appropriate controls and processor equipment is provided to maintain continuous flow of gas into each chamber so as to maintain laser gas concentrations constant or approximately constant at desired levels. This may be accomplished using techniques such as those described in U.S. Patent No. 6,028,880 or U.S. Patent No. 6,151,349 or U.S. Patent No. 6,240,117 (bothall of which are incorporated hereby reference).